RELATIVE RATES OF GERMYLENE AND SILYLENE INSERTIONS INTO ALKYLGERMANES IN COMPETITION WITH DIGERMANE AND DI-SILANE

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SUMMARY

The relative rates of GeH₂ insertions into the Ge-H bonds on a per bond basis were found to be in the order: $(CH_3)_3$ GeH $>(CH_3)_2$ GeH₂ $>$ Ge₂H₆ $>$ CH₃ GeH₃. These results were determined from competitive reactions of GeH₂ with $Ge₂H₆$ and alkylgermanes. The relative rates of SiH₂ insertions into $Si₂H₆$ versus (CH₃)₂GeH₂ and $(CH₃)₃$ GeH were also obtained.

These relative rates and those previously reported were examined for a correlation with the bond energy of the bond undergoing insertion and with the negative charge of the hydrogen in the bond undergoing insertion. The correlation with bond energies was successful for germanes or silanes considered separatively but not for $SiH₂$ insertions into CH₃SiH₃, CH₃GeH₃ and CH₃PH₂. The correlation with the negative charge on the hydrogen was unsuccessful only where steric factors could be important.

INTRODUCTiON

The chemistry of the germanium analogs of methylene has generally been limited to the germanium dihalides. Reactions of germylene (GeH,) have been reported from recoiling germanium atoms¹ and from the pyrolysis of Ge₂H₆². Although GeH₂ insertion into Ge-H bonds has been demonstrated^{1,2}, little is known concerning its chemistry. In connection with a recent investigation of silylene insertion reactions³, a study of relative germylene insertion rates was undertaken by examining competitive insertions of GeH_2 into Ge_2H_6 and other hydrides. In this paper, we report the results of that study and present some generalizations concerning the chemistry of SiH_2 and GeH_2 .

RESULTS

Digermane has been shown to decompose by a 12-hydrogen shift to produce GeH₄ and GeH₂ (Eq. 1)². The reactive intermediate, GeH₂, can insert into Ge₂H₆ to form Ge₃H₈ (Eq. 2) or polymerize on the wall².

$$
Ge2H6 \rightarrow GeH4 + GeH2
$$
\n
$$
GeH2 \rightarrow Ge2H6 + Ge3H8
$$
\n(1)\n(2)

Since the trigermane insertion product is slightly less stable than digermane, the insertion reactions were carried out in a recirculating flow system containing a Iow temperature trap which removed the Iess volatile (and often less stable) products from the stream. AII of the trapping agents used were stable at the reaction temperature (except digermane).

A. Insertion reactions of GeH,

The results listed in Table 1 were obtained from the flow pyrolysis of digermane at 280° in the presence of a second GeH, trapping agent. The relative insertion rates of germylene into the methylgermanes and trimethylsilane can best be compared on a per-bond basis.

The results listed in Table 1 are valid provided that the insertion products did not decompose before they were removed from the reaction stream by the cold trap. Control reactions with deuterated trapping agents demonstrated that secondary reactions did not occur in our system.

TABLE 1

 γ , γ , γ

RELATIVE INSERTION RATE OF GeH, AT 280°C (per E-H bond, E =Si or Ge)

Experiment	Trapping agent	Insertion product	Relative insertion rate 1.0		
-1	Ge_2H_6	Ge ₃ H _a			
2	(CH ₃) ₃ GeH	$1,1,1-(CH3)3Ge2H3$	$1.8 + 0.2$		
3	$(CH_3)_2$ GeH ₂	$1,1-(CH_3),Ge_2H_4$	$1.3 + 0.15$		
4	CH ₃ GeH ₃	$CH3Ge2H5$	$0.8 + 0.1$		
5	(CH ₃) ₃ SiH	(CH_3) , SiGeH,"	< 0.01 ^a		

^a Insertion product not observed.

The pyrolysis of Ge_2H_6 in the presence of CH_3GeD_3 produced methyldigermane- d_3 (presumably $\tilde{C}H_3GeD_2GeH_2D$). This methyldigermane is expected to decompose via a 1,2-hydrogen shift (similar to $Ge₂H₆$) and produce among other products GeH₂D, (Eq. 3a-3c). The methyldigermane- d_3 -trigermane fraction obtained

$$
\begin{array}{ccc}\nD & H & \longrightarrow CH_3GeD_3 & + GeH_2\n\end{array} (3a)
$$

$$
CH3GeGeD \longrightarrow CH3GeD2H + GeHD
$$
 (3b)

$$
\dot{D} \dot{H} \qquad \xrightarrow{\mathbf{L}} \mathrm{GeH}_2\mathrm{D}_2 \qquad + \mathrm{CH}_3 \mathrm{GeD} \tag{3c}
$$

from our control reaction was pyrolysed at 295° for 15 minutes and the volatile products included GeH₂D₂ as expected.

The absence of \overline{GeH}_2D_2 from the 280° pyrolysis of Ge_2H_6 with CH_3GeD_3 demonstrates that methyldigermane was quantitatively removed in our system. Since the methylated digermanes are of similar stabilities and slightly more stable than digermane⁴, these results imply that 1,1- $(CH_3)_2$ Ge₂H₄ and 1,1,1- $(CH_3)_3$ Ge₂H₃ were

also quantitatively removed in our flow system. If GeH₂ did insert into (CH_3) , SiD to form $(CH_3)_3$ SiGeH₂D, and if this compound decomposed prior to condensation in the low temperature trap, $(CH_3)_3$ SiH would probably be a product since SiH₃GeH₃ decomposes solely to $\overline{SH_4}^5$. The absence of $(CH_3)_3SH$ in our control experiment suggests that GeH, did not insert into (CH_3) , SiH.

Although a control reaction to verify the complete removal of $Ge₃H₈$ could not be performed (due to the difficulty in preparing large quantities of Ge_2D_6 and the lack of data on the modes of trigermane decomposition), arguments will be presented to support this contention. Trisilane was shown to be quantitatively removed in the pyrolysis of $Si₂H₆³$. Trigermane was found only slightly less stable than Ge₂H₆ when mixtures were co-pyrolysed, while $Si₃H₈$ is considerably less stable than $Si₂H₆$. In addition, there is a larger difference in volatility between di- and trigermane than there is between di- and trisilane. Thus, both factors which determine the effectiveness of product removal (high thermal stability and low volatility) are favored for $Ge₃H₈$ and therefore it should have been removed as well as $Si₃H₈$ was in the $Si₂H₆$ pyrolysis. It is well to note that even if some $Ge₃H₈$ had decomposed, its effects would be similar in each of the experiments (exp. 2-5) and the results would not lose their significance in a relative sense.

The pyrolysis of Ge_2H_6 was also carried out in the presence of CH_3SiH_3 without the formation of $CH_3SiH_2GeH_3$. However, it appears that $CH_3SiH_2GeH_3$ is more volatile than $Ge_2H_6^5$ and it may not have been retained in our cold trap. Data from the pyrolysis of GeH₃SiH₃ in the presence of CH₃SiH₃ suggest that GeH₂ insertion into the Si-H bond in $CH₃SiH₃$ does occur but with a rate an order of magnitude slower than into the Ge–H bond in GeH₃SiH₃⁵. Results from recoiling germanium atoms in the presence of $GeH₄$ and $SiH₄$ suggest that the relative insertion rate¹ of GeH₂ into GeH₄ and SiH₄ is about $4/1$.

B. Insertion reactions of SiH₂

Table 2 consists of new data on silylene insertions into the methylgermanes

TABLE 2

RELATIVE INSERTION'RATE OF SiH2 AT 350°C (per E-H bond, E **=Si or Ge)**

^a Ref. 3. ^b Ref. 21. ^c This work. ^d Insertion product not observed. ^e See experimental section.

as well as previously reported insertion rates included for ease of comparison. The control experiments required are described in our earlier paper³ which demonstrated the $Si₃H_g$ was quantitatively removed by the cold trap and that CH₃GeH₂SiH₃ was almost quantitatively *removed* from the stream. Di- and trimethylgermane are stable at 350".

DISCUSSION

The relative rates of GeH₂ insertion into Ge-H bonds in monogermanes (exps 2-4 in Table 1) and of SiH, insertion into Si-H bonds in monosilanes (exps 2-6 in Table 2) correlate well with the Ge-H or Si-H stretching frequencies. For silicon and germanium, *these* stretching frequencies decrease as methyl groups replace hydrogen atoms and increase as chlorine replaces hydrogen. As the frequency decreases, the insertion rate increases. The stretching frequencies can be related to both the charge on the hydrogen atom and the bond strength. A decrease in stretching frequency corresponds *to* decrease in bond strength. This corresponds to an increase in the " p " character of the germanium or silicon orbital bonded to hydrogen which also corresponds to an increase in the negative charge on the hydrogen^{7.8}. The increased rates of insertion for GeH_2 into $Ge-H$ bonds and SiH_2 into $Si-H$ bonds can thus be correlated with either a decrease in E-H bond strength ($E = Si$ or Ge) or an increase in the negative charge on the H atom undergoing insertion.

The low insertion rate for GeH₂ into $(CH_3)_3$ SiH in competition with Ge₂H₆ (exps 1 and 5 in Table 1) and the high insertion rates of $SiH₂$ into (CH₃)₂GeH₂ and $(\text{CH}_3)_3$ GeH in competition with Si_2H_6 (exps 1, 7 and 8 in Table 2) could be explained on the basis of bond energies. That is, the insertion rate is faster into the *weaker* bond. This rationalization would also explain the relative rates of ³HCCl insertion into the Si-H bonds⁹ in (CH₃)₃SiH, (CH₃)₂SiH₂ and SiH₄ which were determined to be $6/1$ / < 0.1. Similarly the insertion of ¹CH₂ into CH₃SiH₃ is favored into the Si-H bonds versus the C-H bonds by a factor ¹⁰ of 8.9 while CCI₂ insertion into $(C_2H_5)_3$ GeH was found to be 4.5 times greater than into $(C_2H_5)_3SH^{11}$.

However, the regulation of relative insertion rates by bond energies does not appear to explain the *results* of the relative insertion rates of SiH_2 into CH_3SiH_3 *versus* insertion into CH_3GeH_3 or CH_3PH_2 . The Si-H bond energy is greater than that of the Ge-H bond¹² while the Si-H and P-H bond energies are very similar¹². Thus the relative insertion rates of $SiH₂$ into $CH₃SiH₃$, $CH₃GeH₃$ and $CH₃PH₂$ should be in the order, $CH_3GeH_3 > CH_3SiH_3 \cong CH_3PH_2$, and not in the observed order of CH₃SiH₃ > CH₃GeH₃ > CH₃PH₂. The observed order correlates exactly with the charge on the hydrogen ; the greater the negative charge on the hydrogen, the faster the insertion, This rationalization would also be consistent with the HCCI insertions into silanes and that of CH_2 into CH_3 SiH₃. It is interesting to note that the correlation between insertion rates and the negative charge on hydrogen only breaks down in cases where steric factors could be important. The low rate of $GeH₂$ insertion into (CH_3) , SiH versus (CH₃)₃ GeH and the high rate of SiH₂ insertion into (CH₃)₃ GeH and (CH_3) , GeH₂ versus (CH₃)₃ SiH and (CH₃)₂ SiH₂ respectively could be due to or at least affected by steric factors. Similarly, the greater rate of CCI_2 insertion into $(C_2H_5)_3$ GeH versus $(C_2H_5)_3$ SiH could also be due to steric factors.

EXPERIMENTAL

Reagents. Disilane, methyIsiIanes, methylgermane, and trimethyIgermane were prepared by the reduction of the corresponding chlorides with $LiAlH_a$ or $LiAlD_a$. Dimethylgermane was prepared from methylgermane as described by $J01y^{13}$. Digermane was prepared from the static pyrolysis of $GeH₄$ at 340° (350 mm) for intervals of 1-2 min. Germane was obtained from the NaBH₄ reduction of GeO₂¹⁴. These reagents were purified by trap to trap distillations and were identified by infrared and mass spectra. The purity of these compounds was demonstrated by GLPC as well as by demonstrating that infrared bands and mass spectral peaks of *logical* impurities were absent from the spectra of these compounds.

Instrumental. Infrared spectra were recorded on a Perkin-Elmer 337 or 621 spectrophotometer while mass spectra were obtained on a Hitachi-Perkin-Elmer RMU-6E spectrometer. The product hydrides were separated by GLPC as previously described'.

General procedure. The pyrolyses were carried out in a recirculating flow system consisting of a Toepler pump, thermal zone and "U"-trap. The thermal zone was a 10 cm \times 10 mm O.D. pyrex tube heated by means of a high temperature tape and insulated with magnesia insulation. Temperatures were measured by means of a thermometer inserted in a pyrex well between the heating tape and the thermal zone. The temperature was regulated by a constant voltage power supply. The pyrex thermal zone was coated with a silicon mirror from silane decompositions for the $Si₂H₆$ pyrolyses and coated with a germanium mirror for $Ge₂H₆$ pyrolyses to avoid pyrex catalysis.

Analysis. Authentic samples of the reaction products were obtained from the pyroIysis of digermane or disilane with the appropriate trapping agent as indicated in Tables 1 and 2. The infrared spectra of Ge₃ H₈¹⁵, CH₃ Ge₂ H₅¹⁶, 1,1-(CH₃)₂ Ge₂ H₄¹⁷ 1,1,1-(CH₃)₃Ge₂H₃¹⁸, and 1,1,1-(CH₃)₃GeSiH₃¹⁹ were identical to those in the literature. The mass spectra of these compounds were consistent with their formulae_ The previously unreported compound $1,1-(CH₃)₂ GeHSiH₃$ is described below. Authentic product and reagent samples were used to determine GLPC retention times and weight correction factors.

Al. *Competitive reactions with Ge,H, at 280°C*

The data in Table 3 represent the average of at least three identical reactions for each system. The pyroIysis cold traps listed in Table 3 were used during the pyrolyses. After each reaction, the mixture was fractionated and the product was condensed in the condensation cold trap as listed in Table 3.

A2. Control reactions with $Ge₂H₆$

CH3GeD3. Methylgermane-d, and digermane (0.92 mmol each) were pyrolysed at 295° for 6 h with a -63° cold bath. The germane fraction (pass -160° , stop -196° ; 0.33 mmol) was analyzed by infrared and mass spectrometry for the presence of deuterated germanes. The infrared spectrum was primarily that of $GeH₄$ with very weak absorptions at 706 and 901 cm⁻¹ due to GeH₃D²⁰. Some GeD₃H (595, 625) and 790 cm^{-1})²⁰ may also have been present. Absorptions due to GeH₂D₂ (657, 770) and 880 cm⁻¹/²⁰ were absent. Mass spectral results are tabulated below. The fraction

TABLE 3

TABLE 4

PARTIAL MASS SPECTRA OF THE GERMANE FRACTION AFTER PYROLYSIS

m/e	76	-77	78	79	80	81
Pure $GeHA$	1000	805	165	165		0
Pass -160° fraction from $Ge, H6-CH3GeD3$	1000	785	230	160	22	0
Pass -160° fraction from product pyrolysis	1000	810	400	200	65	35

which passed -78° and stopped at -95° was pyrolyzed for 15 minutes at 295° without a cold bath. The germane fraction from this second pyrolysis was too small **for infrared analysis, but the mass spectrum (Table 4) indicated the presence of** GeH_2D_2 from the decomposition of the GeH_2 insertion product (presumably $CH₃GeD₂GeH₂D$).

 (CH_3) , SiD. Trimethylsilane-d, and Ge_2H_6 were pyrolysed as shown in exp. 4, Table 3. The infrared spectra of all fractions obtained did not contain absorptions due to Ge-D bonds (approx. 1500 cm⁻¹) or to Si-H bonds (approx. 2120 cm⁻¹).

B1. Competitive reactions with $Si₂H₆$ *at 350°*

The following data **represent average results of at least three identical reactions.** $(CH₃)₃ GeH$. A mixture of 1.47 mmol of $(CH₃)₃ GeH$ and 0.30 mmol of $Si₂H₆$ were pyrolyzed for 6 h with a -78° bath. The gas phase ratio $\rm Si_2H_6/(CH_3)_3GeH$ was 1.6. The small quantities and very large retention time of $(CH_3)_3$ GeSiH₃ precluded **determination of the GLPC weight correction factor and accurate measurement of** peak areas. The stop -112° fraction consisted of a 2.5 \pm 1 excess of $Si₃H₈$ over $(CH₃)₃$ GeSiH₃.

 $(CH₃)₂ GeH₂$. Dimethylgermane (0.58 mmol) and disilane (0.48 mmol) were pyrolyzed with a -78° trapping bath which set the gas phase ratio at 0.34. After 6 h, the stop -112° fraction contained $(CH_3)_2$ GeHSiH₃/Si₃H₈ (=0.71).

B2. *Identification of (CH,),GeHSiH,*

The dimethylgermylsilane prepared in exp. 8 (Table 2) was identified as follows: (i) The gas phase infrared spectrum consists of the following absorptions: 2975 m, 2920 m, 2146 vs, 2029 s, 1381 w, 1250 w, 922 m, 878 s, 828 vs, *705* **m, 669 m, 585 m cm- I. (ii) The mass spectrum consisted of peaks due to the heavy atom skeletons** (envelope intensity); C_2 GeSi⁺ (20.8), C GeSi⁺ (47), GeSi⁺ and C_2 Ge⁺ (100), C Ge⁺ (61.7), Ge⁺ (18.3). At higher voltages CSi⁺ fragments were observed due to methyl migration as reported for (CH_3) , GeSiH, by Mackay *et al.*¹⁷.

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